

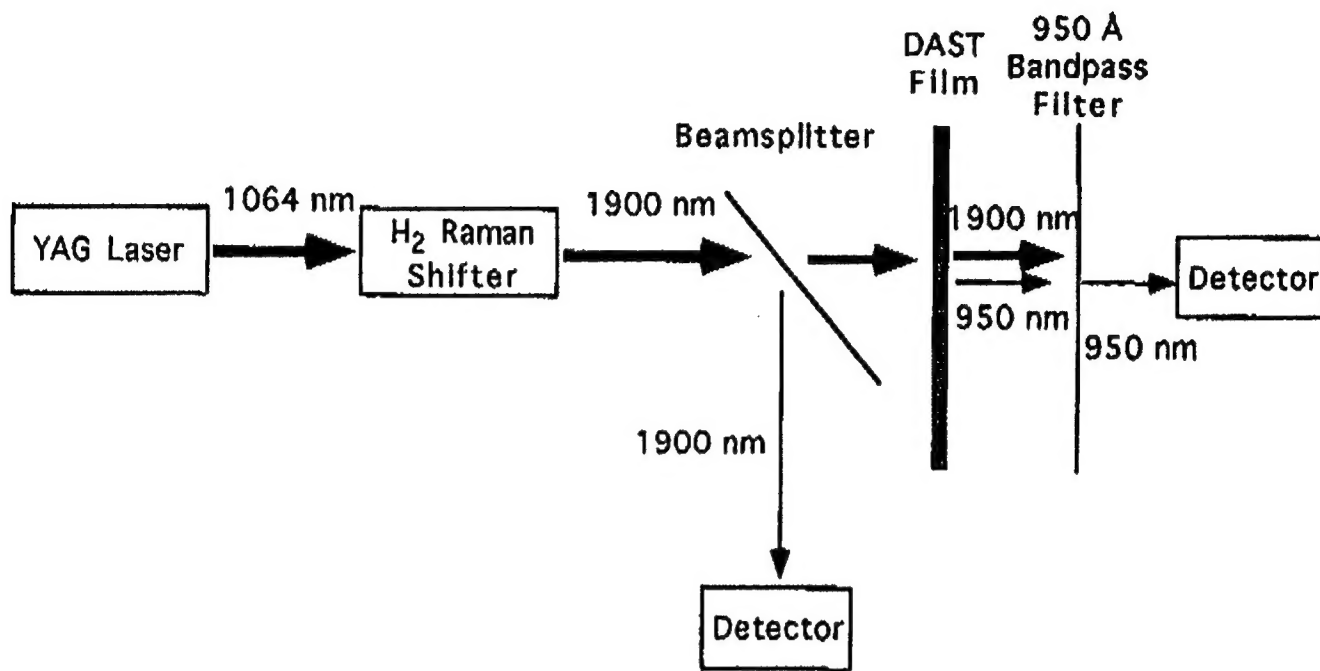
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13. ABSTRACT (Maximum 200 words) NMR spectroscopy identified the main impurity in DAST films grown by OVPD method. The impurity is a trimethylated compound described in last month report. Thus our films consist of over 90 % DAST and some 5 to 10 % of the above impurity. An apparatus for measuring second harmonic generation properties of OVPD DAST films has been constructed and described. We expect to do quantitative measurements this month. We continue the optimization of growth conditions of the OVPD method. This month we shall grow from tosylate starved atmosphere and study effects of substrate nature on optical properties of grown films.				
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Apparatus for measurement SHG activity of DAST films grown by the OVPD method